

ABSTRACT

A holder for maintaining substrates in an array during a high throughput materials deposition comprising a face plate, middle plate and retainer plate attached in sequence and aligned in an axis in which a plurality of cylindrical substrates are maintained in cylindrical chambers formed in an array with respect to the face surface of the block assembly. A spring loading mechanism positions the substrates within the chambers during the processing of the substrates, the substrates are removable from the holder after the completion of processing.